


APPLICATION DATA SHEET

Electronic Version v14

Stylesheet Version v14.0

Title of Invention	Method of Forming Thin Silicon Oxide Films on Silicon Carbide Substrates		
<p>Application Type : regular, utility</p> <p>Attorney Docket Number : 1372.80.PRC</p> <p>Request Not To Publish</p> <p>I/We hereby request that the attached application not be published under 37 U.S.C. 122(b).</p> <p>I/We hereby certify that the invention disclosed in the attached application has not and will not be the subject of an application filed in another country, or under a multilateral agreement, that requires publication at eighteen months after filing.</p>			
<p>Correspondence address:</p> <p>Customer Number: 2901</p> 			
<p>Continuing Data:</p> <p>This is a Non-Provisional of US application number 60/319,607, filed 2002-10-11.</p>			
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as my attorney(s) or agent(s) to prosecute the application identified above, and to transact all business in the United States Patent and Trademark Office connected therewith.

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